

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Jung-Wook Kim, et al.	Examiner: Michail Kornakov
Serial No:	10/606,512	Group Art Unit: 1746
Filed:	June 26, 2003	Docket: 8054-23 (AW8037US)
For:	METHOD FOR CLEANING A PROCESSING CHAMBER AND METHOD FOR MANUFACTURING A SEMICONDUCTOR DEVICE	

Mail Stop: Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action dated March 21, 2007, please amend the above-referenced patent application as set forth herein.
